Supporting Information

for

Spermine-Induced Hybridisation and Charge Inversion at the Diffuse Layer of a DNA-FET

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Field-effect transistor fabrication and instrumentation.

Starting silicon wafers had 0.8-1.4 ohm•cm resistivity. A 0.4 µm-thick oxide was thermally grown and patterned to open the source and drain areas. The FET channel is, as defined in the fotolithography mask, 5 µm long and 500 µm wide. Phosphor-doped n-type regions were formed by ion implantation. A second patterning of the oxide layer was used to remove the thick oxide from the gate area. Subsequently, a 10 nm oxide layer was grown in O₂ atmosphere at 800 °C and a 15 nm nitride layer was deposited by LPCVD (Low Pressure Chemical Vapour Deposition). The fabrication was finished with the dryetch opening of contact areas, deposition of a 0.5 µm aluminum layer and its wet-etch patterning. After wafer dicing, the chips were glued and wire-bonded to a printed circuit board (PCB). Encapsulation was performed by covering the PCB and the chip with a photocurable epoxy resin (Ebecryl 600, UCB Chemicals) and exposing it to UV light through a mask. The uncured polymer on top of the FET gate was removed with ethanol.

A two channel home-made amplifier was used to measure simultaneously the C and NC modified FETs as well as the differential signal. The amplifier keeps the drain current and drain to source voltage constant at $100~\mu A$ and 0.5~V, correspondingly. The amplifier output voltage is the voltage drop from the reference electrode to the source terminal. A double junction Ag/AgCl reference electrode was used. The outer solution was filled up with hybridisation buffer, in order to avoid diffusion of ions from the electrode to the solution. A KUSB3116 data acquisition module and a LabView program in a PC were used to record and store the output signals.

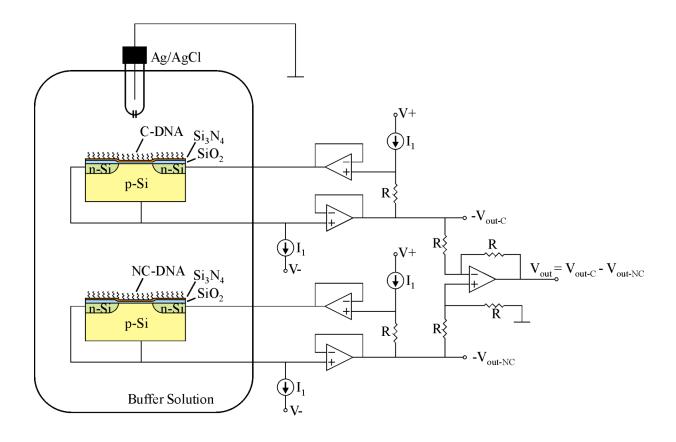


Figure S1. FET cross-section and electrical measurement set-up.